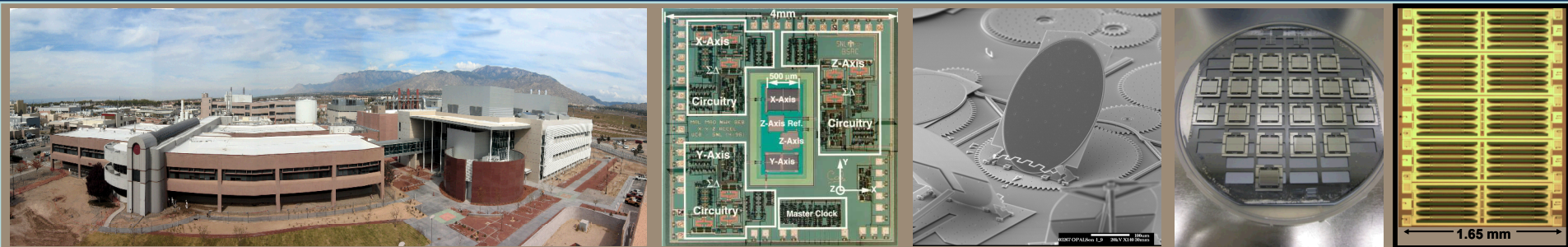


*Exceptional service in the national interest*



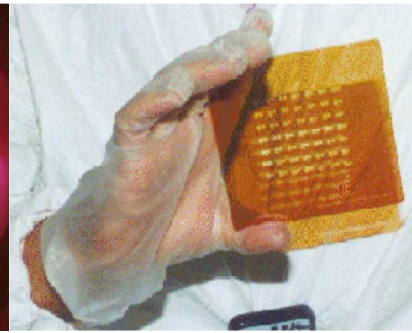
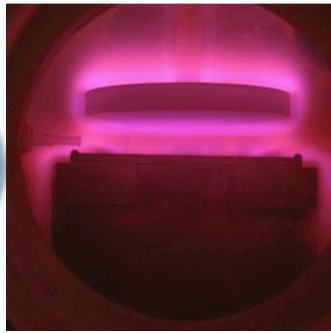
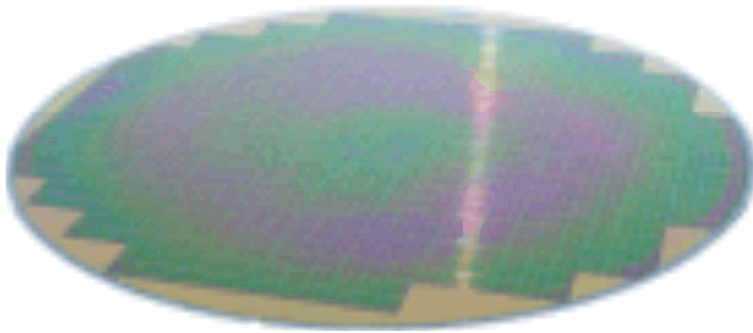
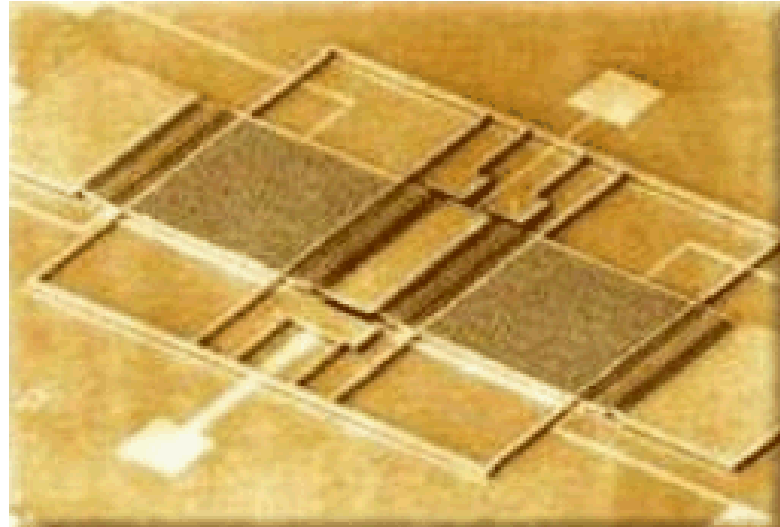
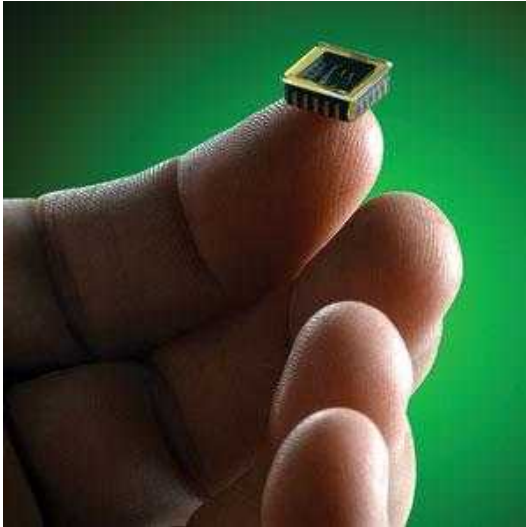
# MEMS at Sandia National Laboratories

November 2012

# MEMS are

# “MicroElectroMechanical Systems”

*Also known as “microsystems”*



# The MEMS Technologies Department

*Pushing the MEMS technology envelope for national security*

## R&D for Advanced MEMS

- Mechanisms
- Pressure Sensors
- Inertial Sensors
- Fluidic Components
- Electrical Switches
- RF Switches
- RF Filters
- Mirrors
- Planar Light Wave Circuits
- Solar Cells
- Radiation Detectors

## Prototype Development and Limited Production

### Core Fabrication Processes

- SUMMiT V™, Baseline plus
  - Silicon Nitride
  - DRIE
  - SOI
  - SFET
- Molded Tungsten
- Aluminum Nitride

### Core Technologies

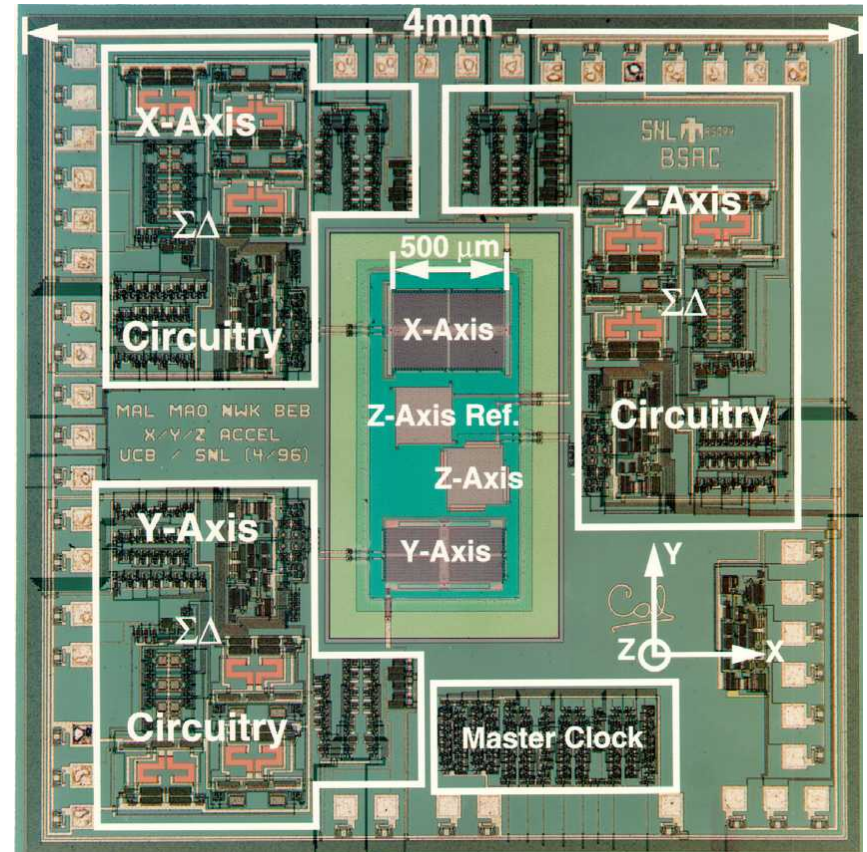
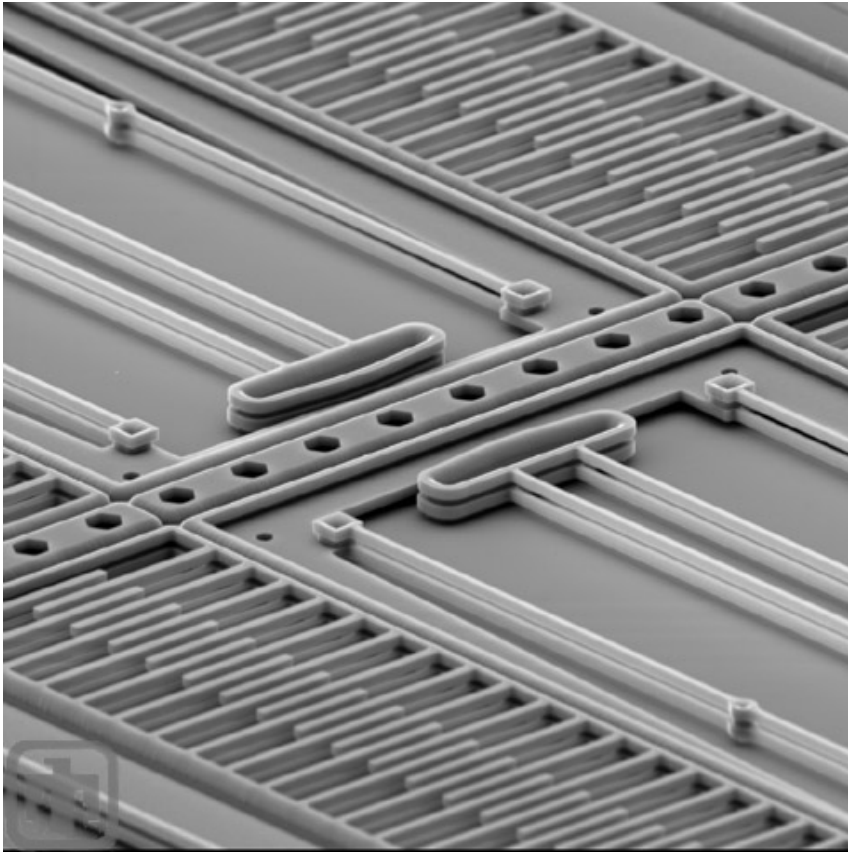
- Design, Layout and Analysis
- Device Testing/Characterization
- Reliability Science and Testing
- Failure Analysis





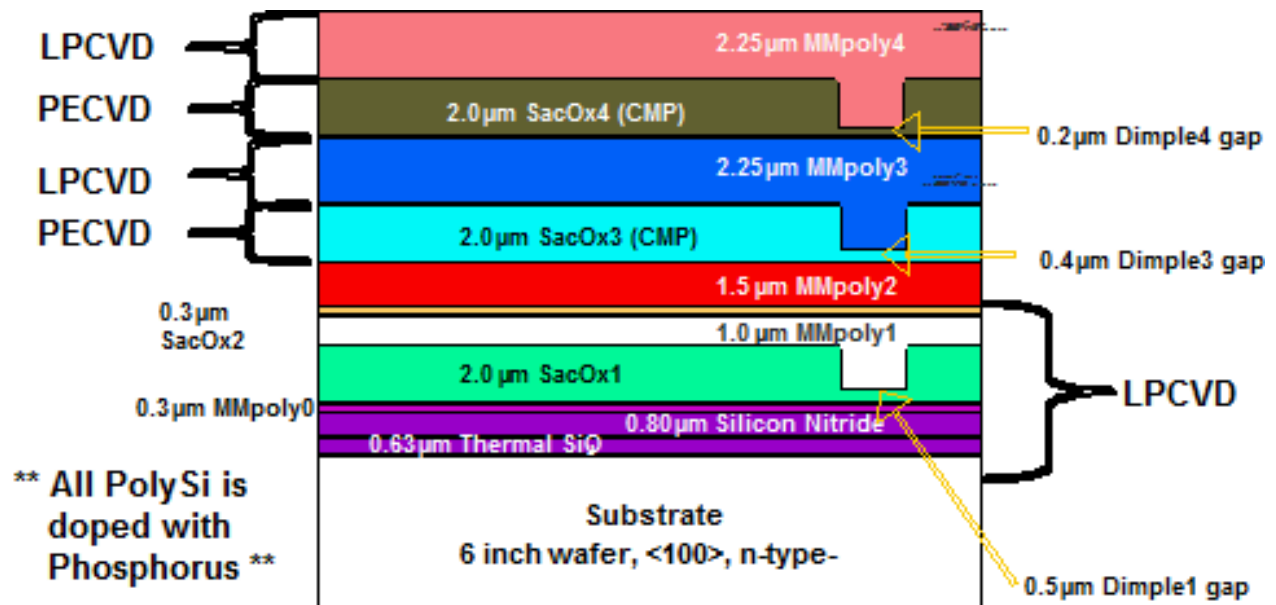
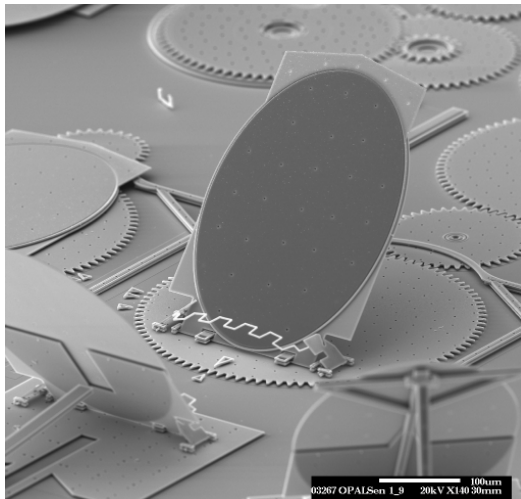
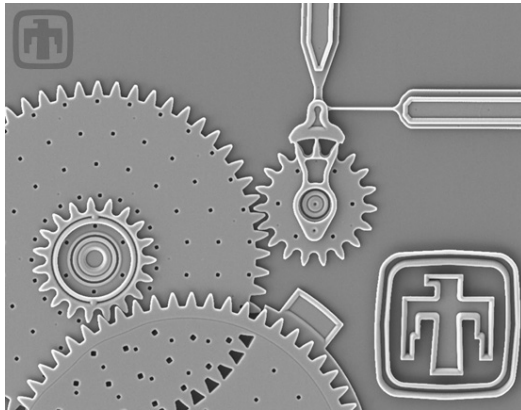
# Sandia's Efforts Started in 1990s

*Collaboration between semiconductor fab and mechanical designers*



# SUMMIT V™: A Unique Capability

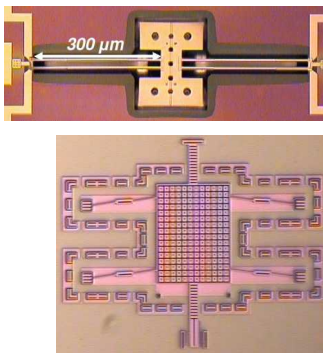
*Sandia Ultraplanar, Multilevel MEMS Technology with 5 polysilicon layers*



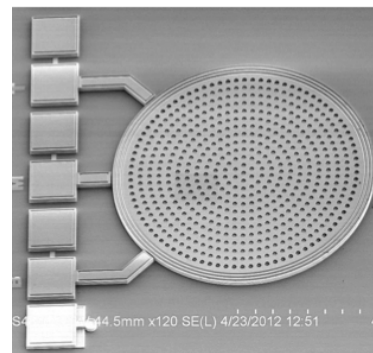
# Sandia's Portfolio Today

*Exploratory research and advanced development for MEMS technologies, devices, and systems for national security.*

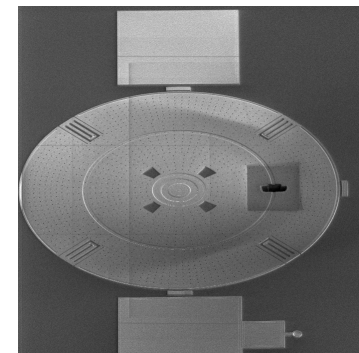
**Inertial Sensors**



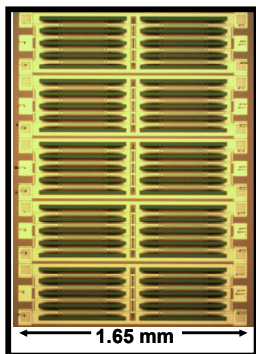
**Pressure Sensors**



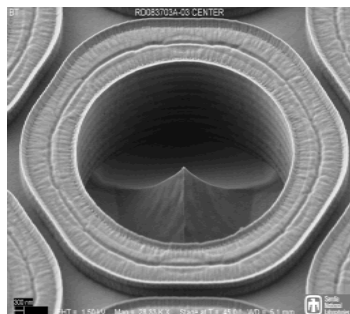
**Microfluidic Actuators**



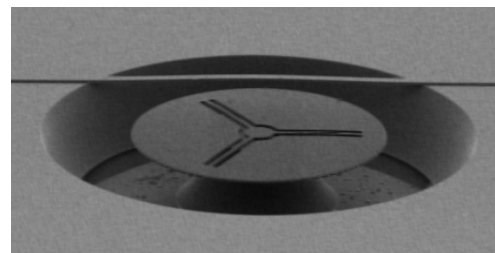
**Electronics**



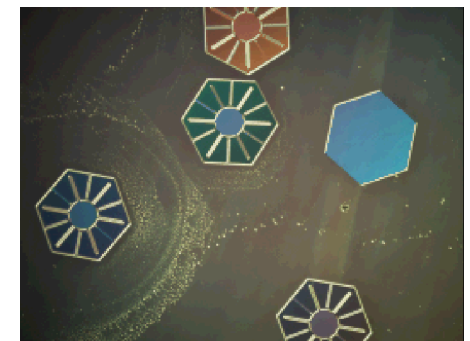
**Vacuum Electronics**



**Photonics and Waveguides**



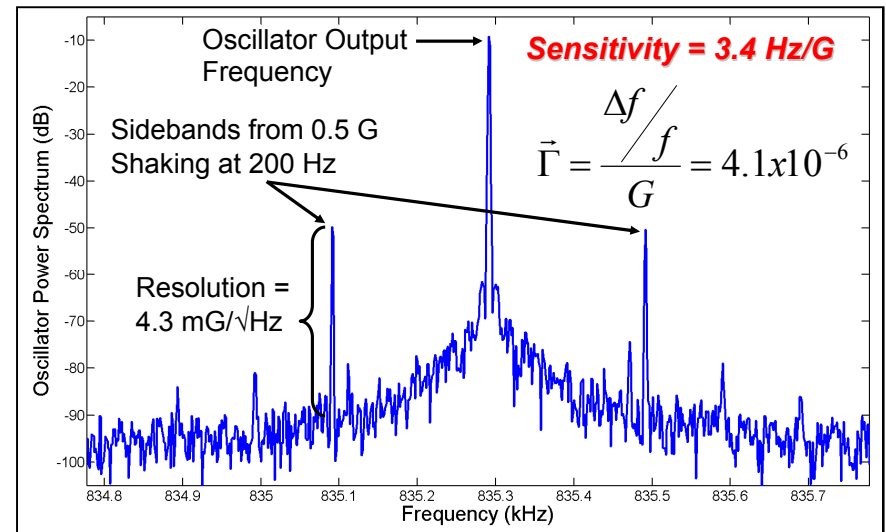
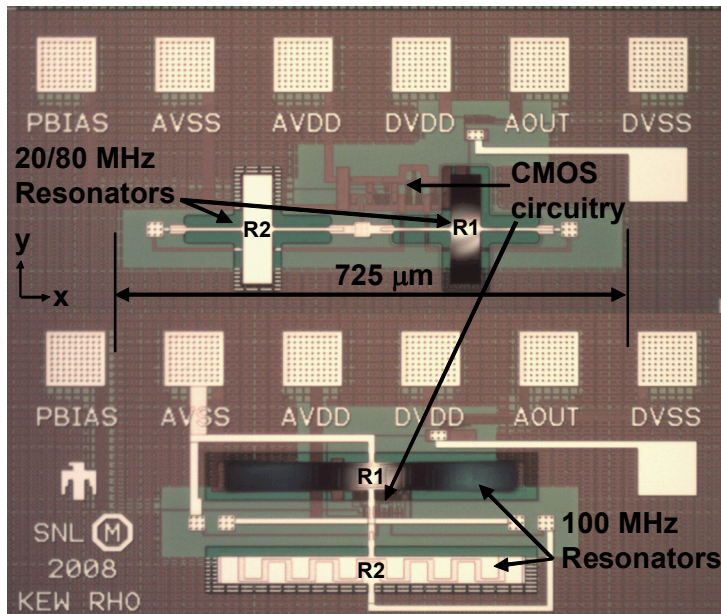
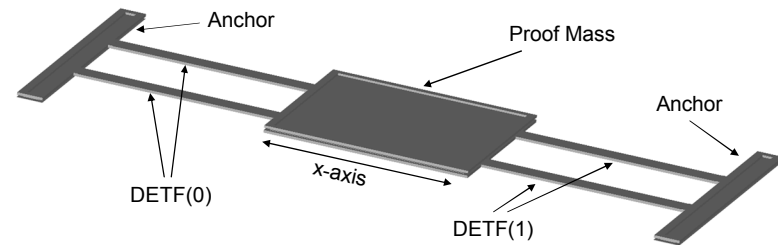
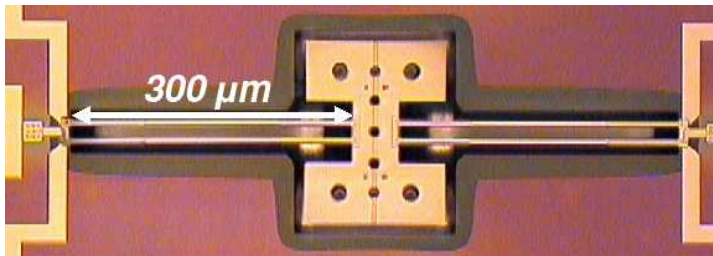
**Photovoltaic Cells**





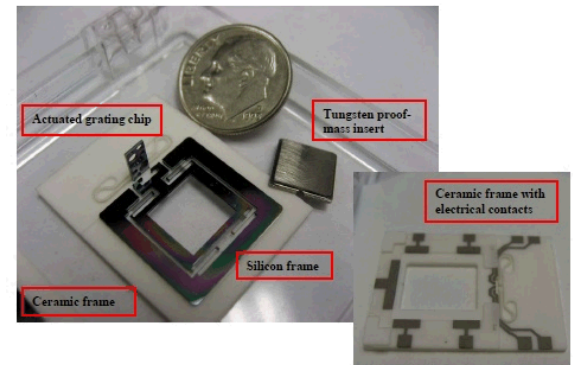
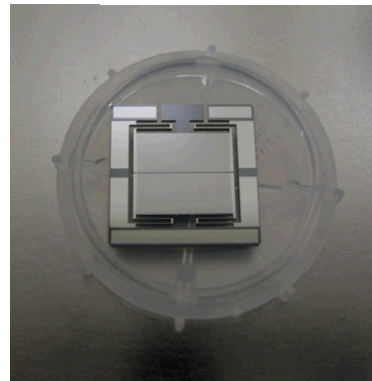
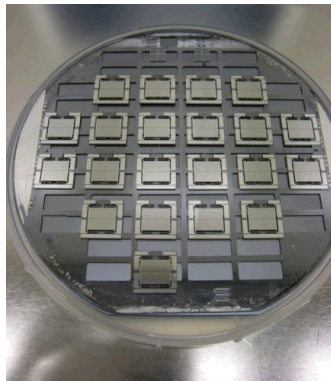
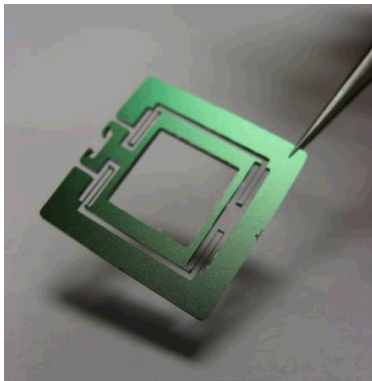
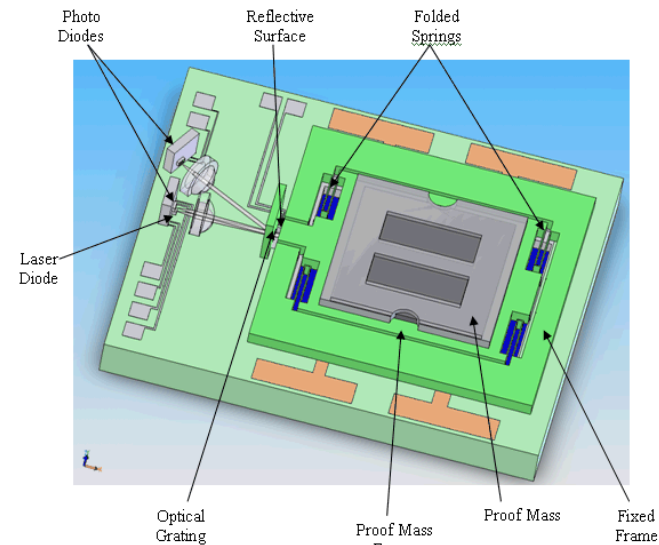
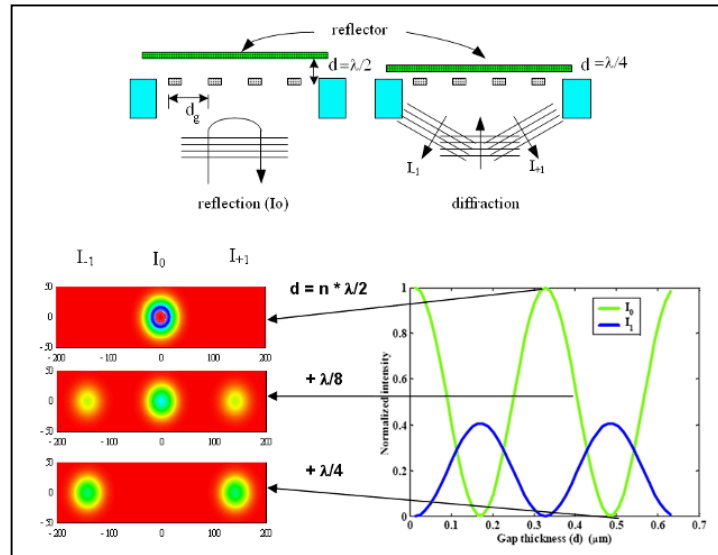
# Inertial Sensors: Radiation-Hard

## Supporting the core nuclear weapons mission



# Inertial Sensors: High Performance

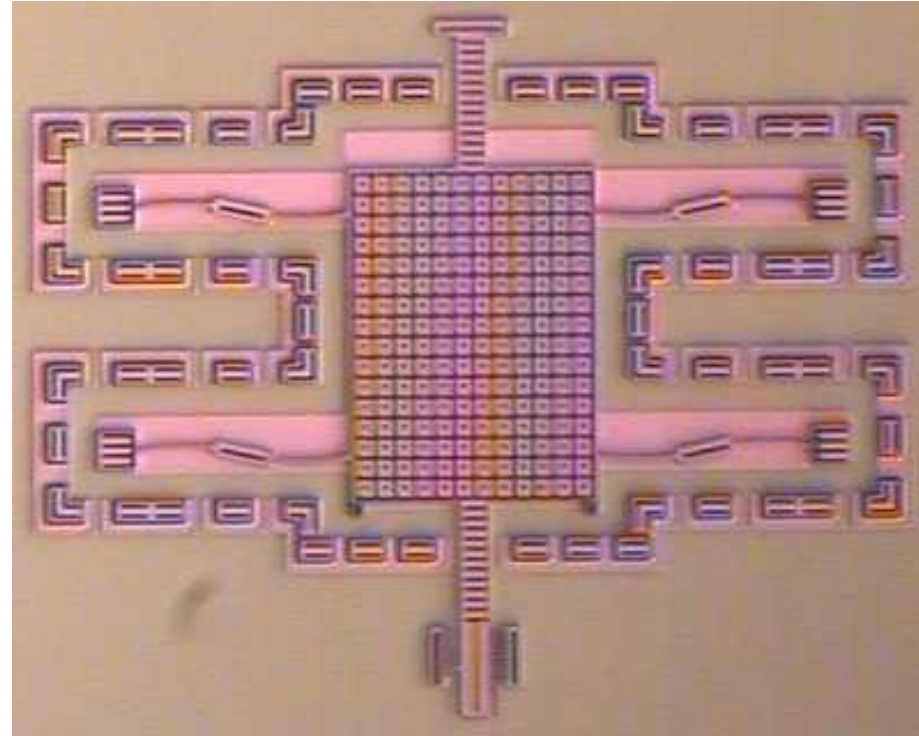
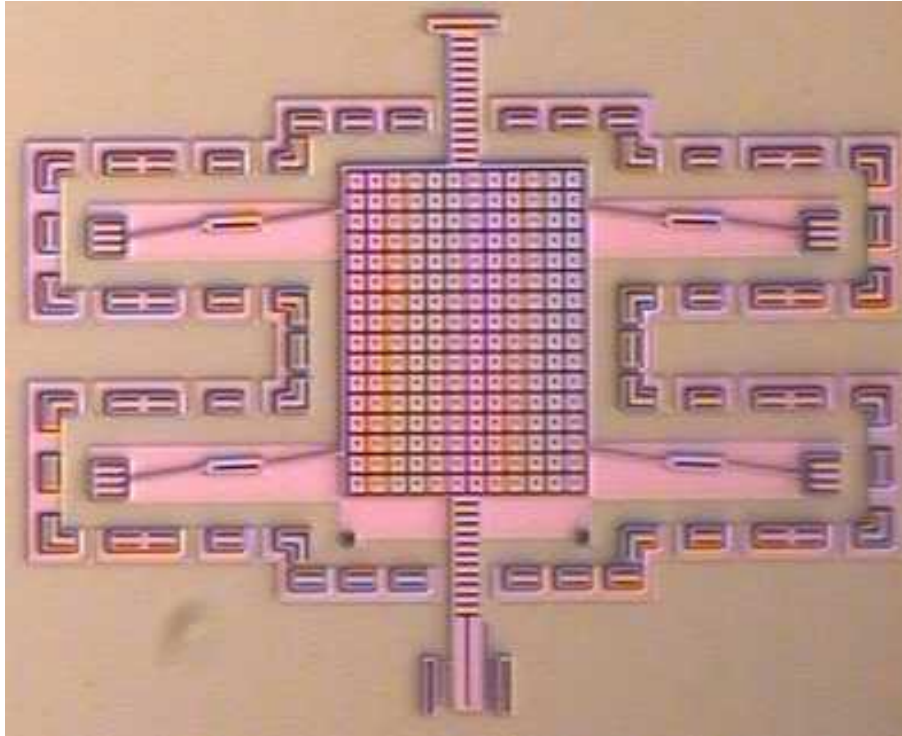
*Complex fabrication, uneconomical for commercial applications*





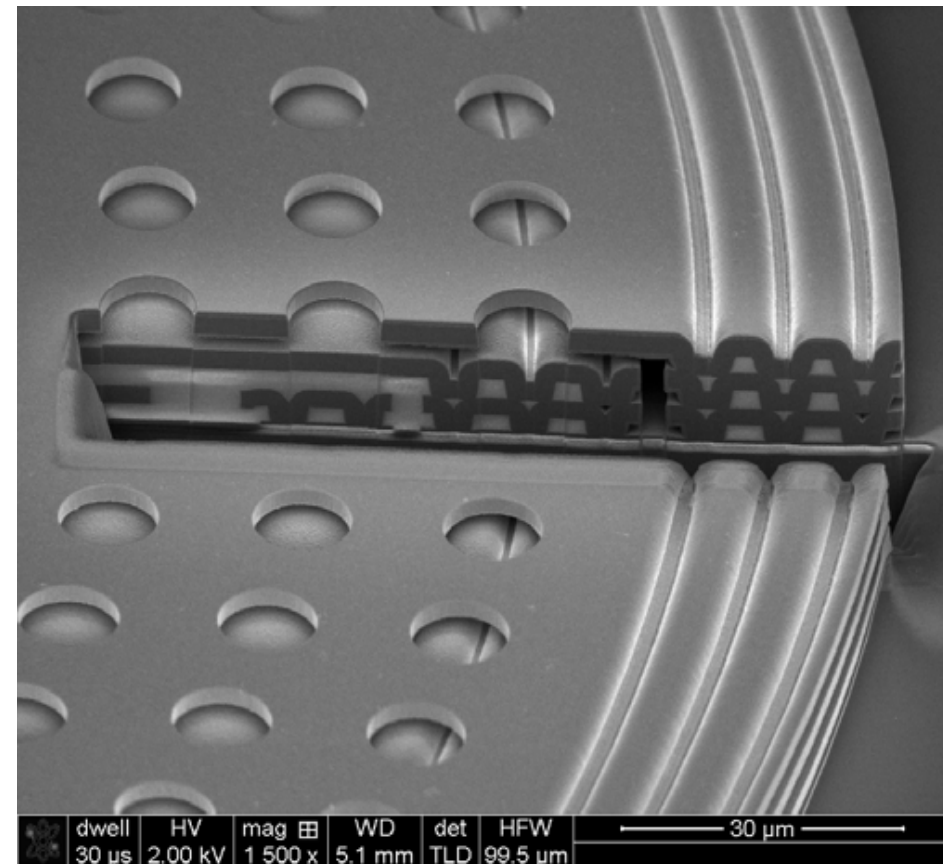
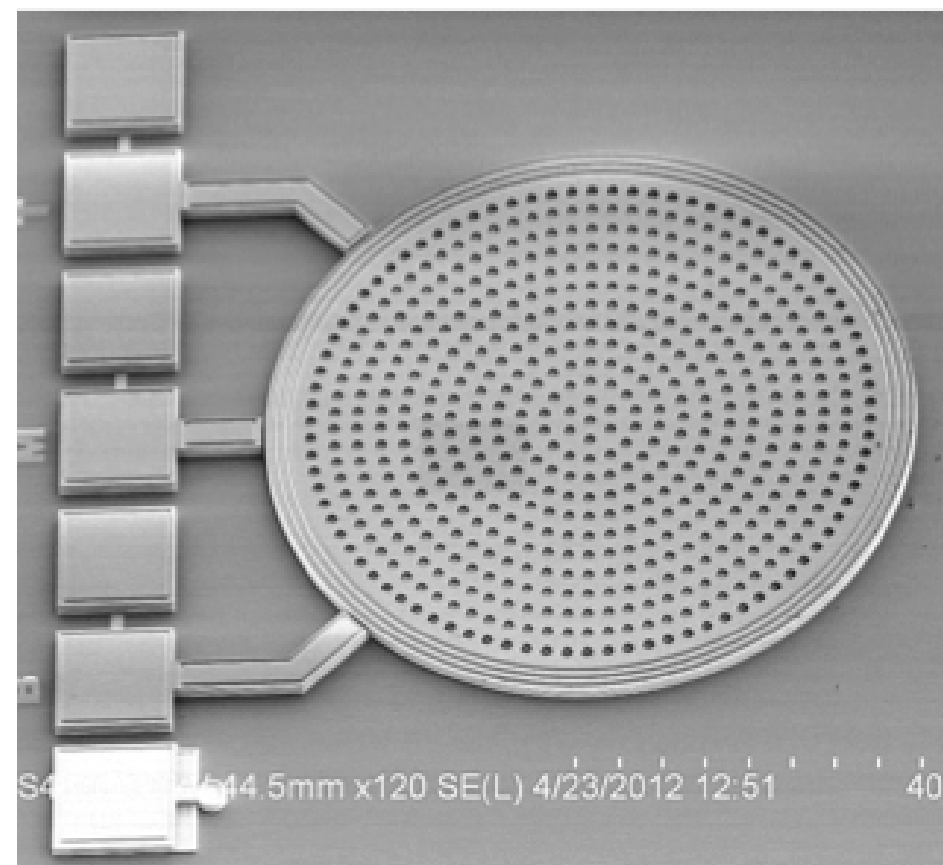
# Inertial Sensors: Novel Devices

*Sensing unique inertial environments*



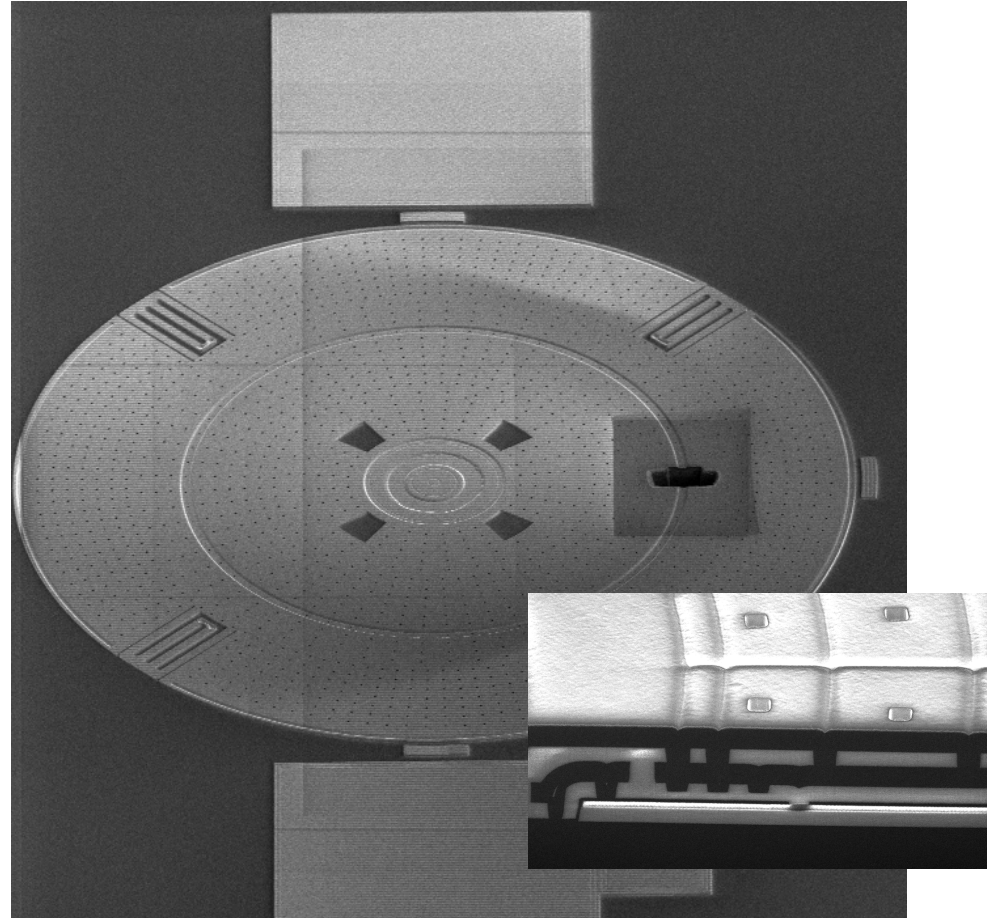
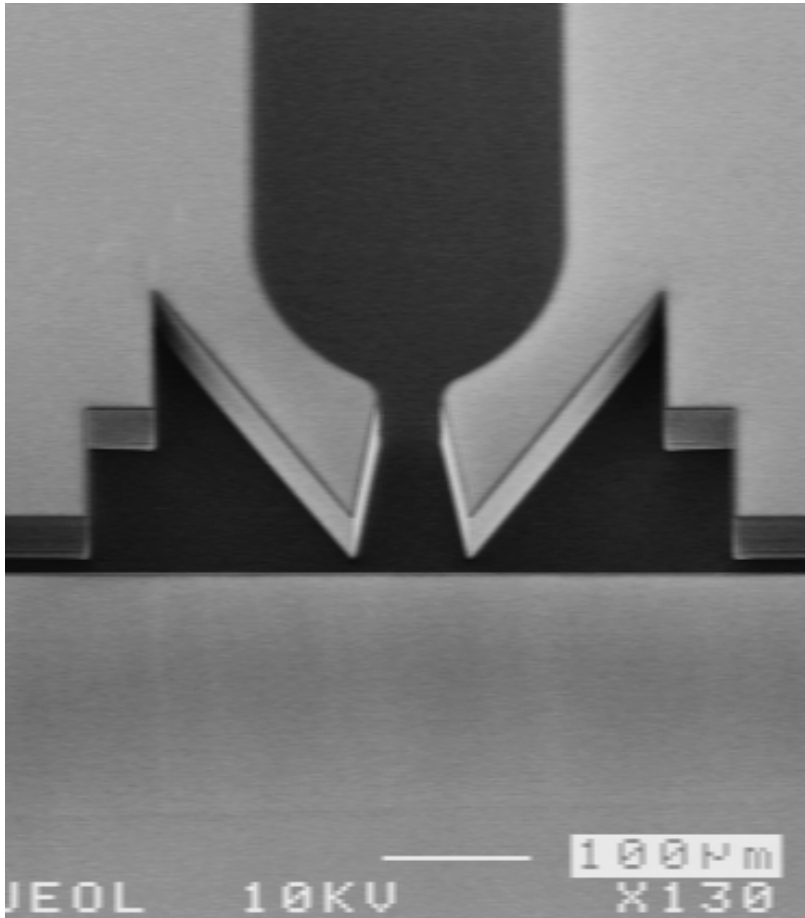
# Pressure Sensors

*And other moving membrane sensors, e.g., microphones*



# Microfluidic Actuators

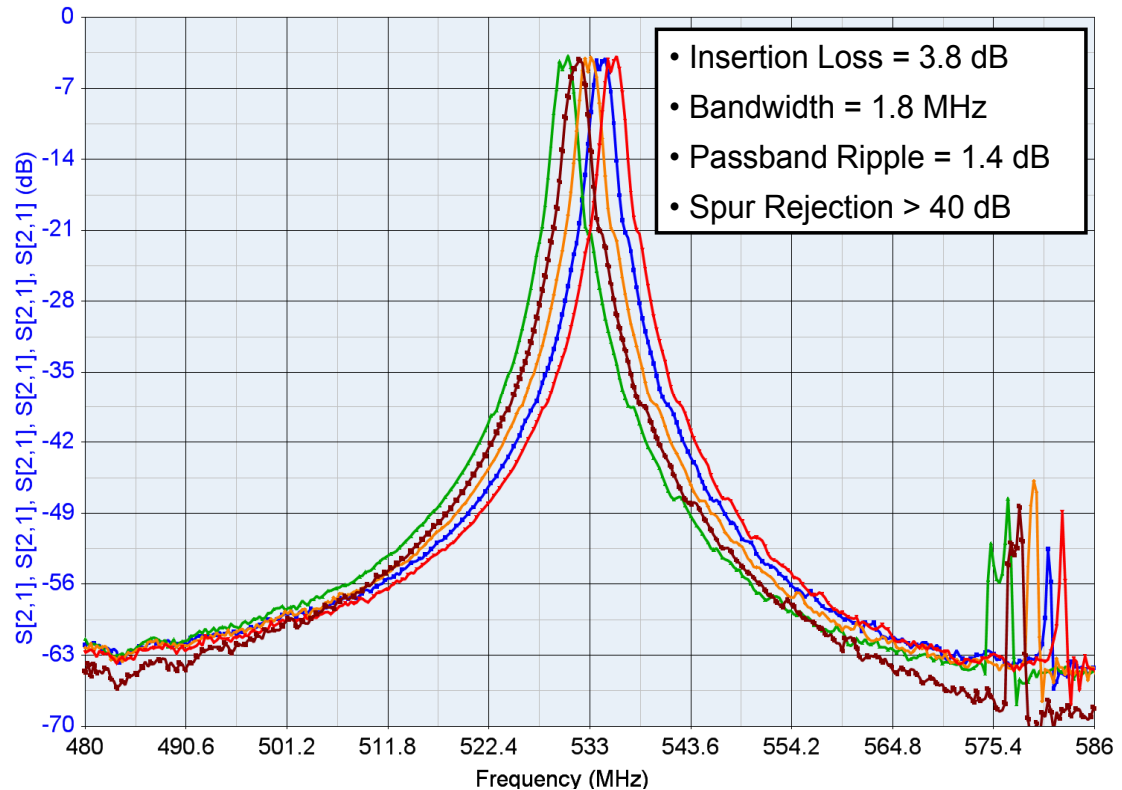
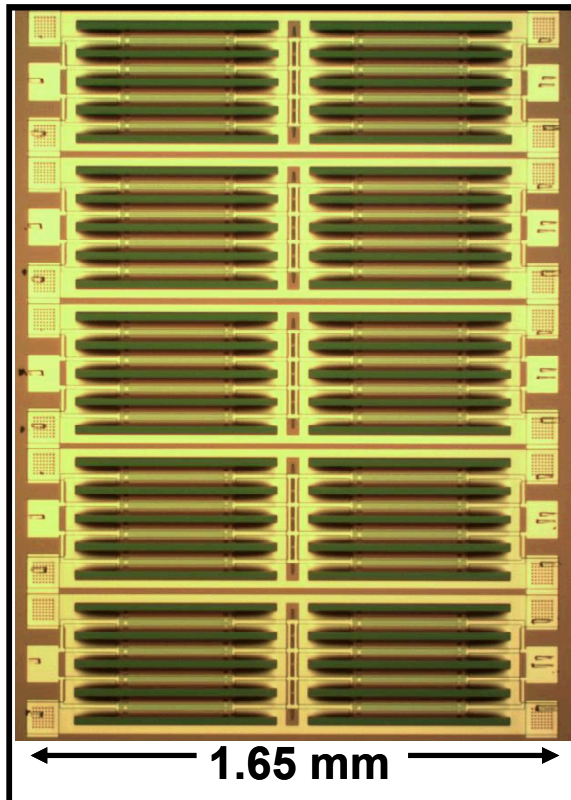
*Jet nozzles, active and passive valves, flow channels, and more*





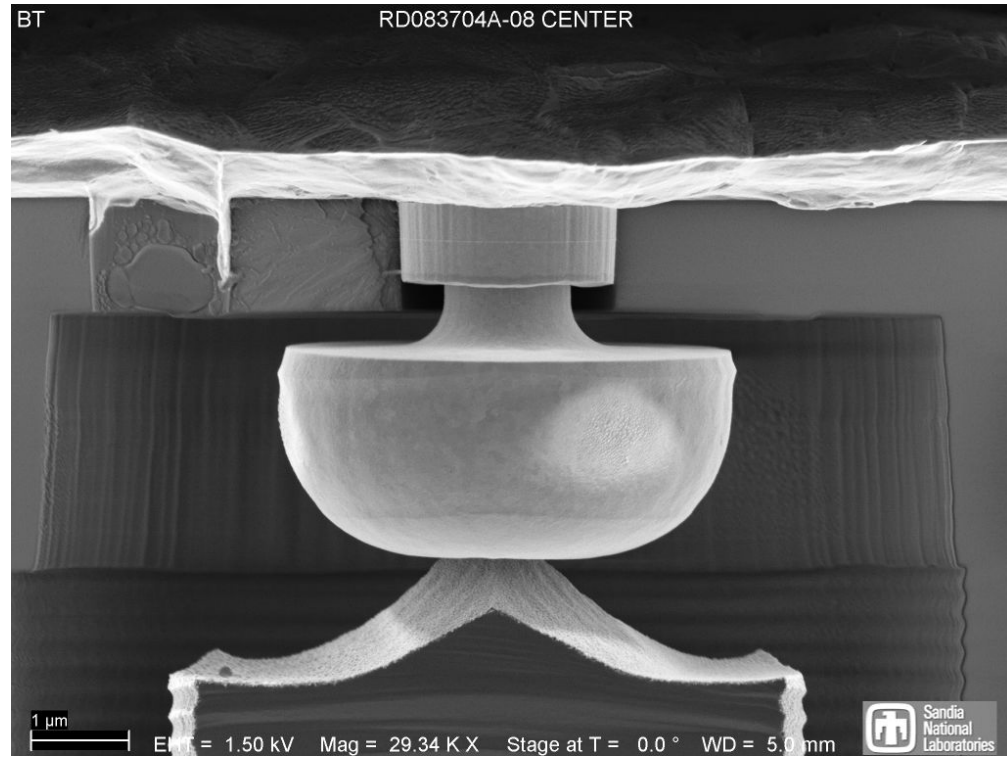
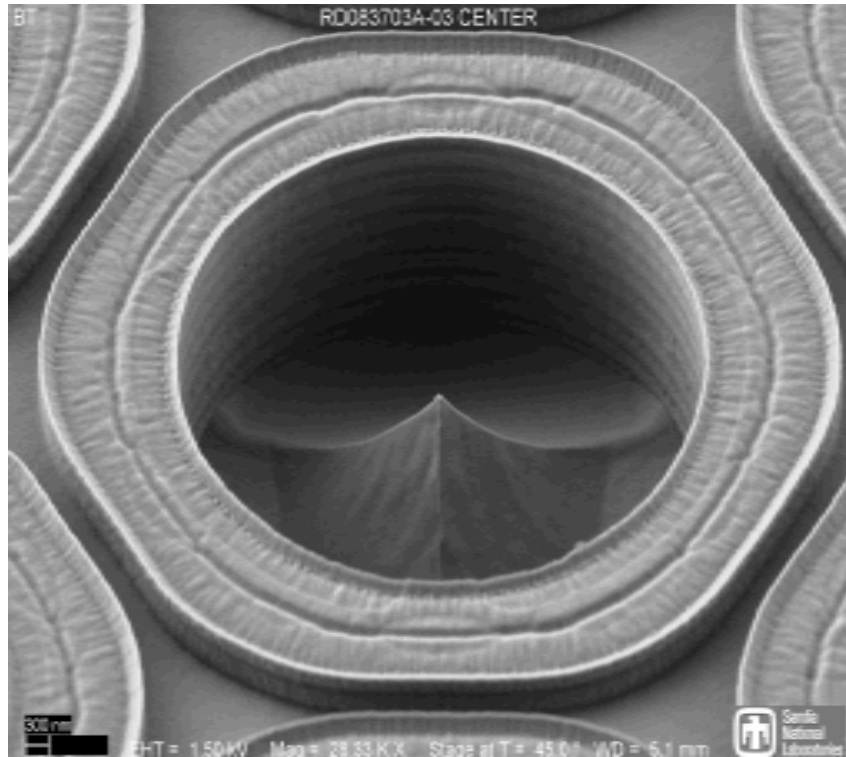
# Electronics: RF Filters and Oscillators

*Filter frequency defined by lithography; multiple filters on a chip*



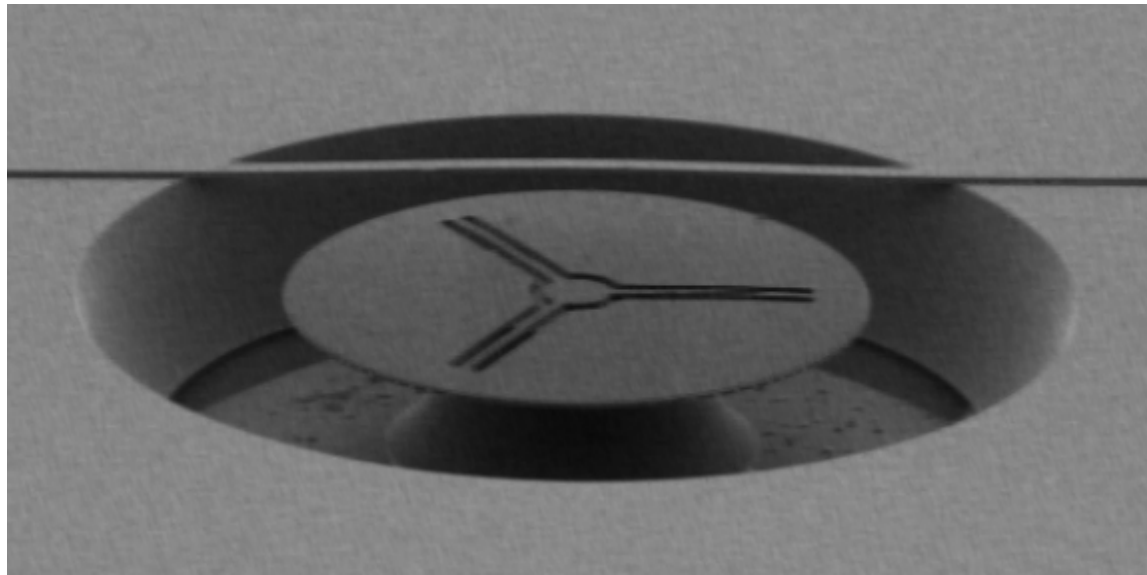
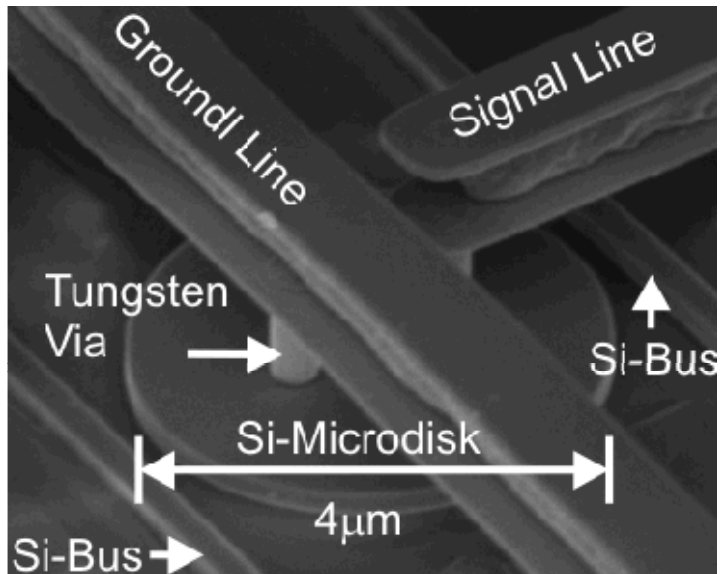
# Vacuum Electronics

*Monolithically fabricated vacuum devices, e.g., diode*



# Photonics and Waveguides

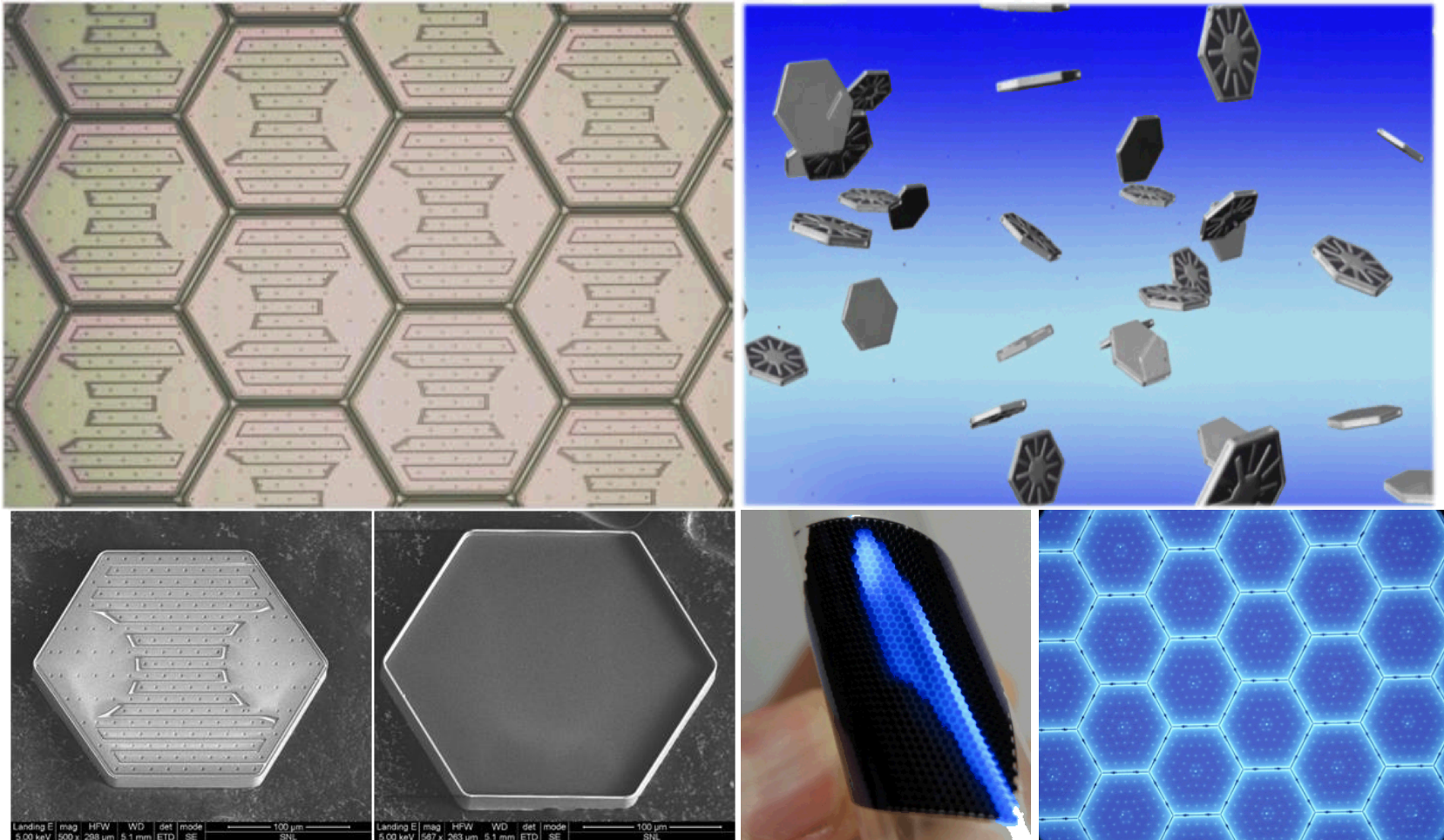
*Low loss waveguides and ring resonators for optical signal processing*





# Microsystems Enabled Photovoltaic Cells (MEPV)

*Microsystems technologies are creating disruptive change in PV*



# Contact Information

Keith Ortiz

[Keith.Ortiz@sandia.gov](mailto:Keith.Ortiz@sandia.gov)

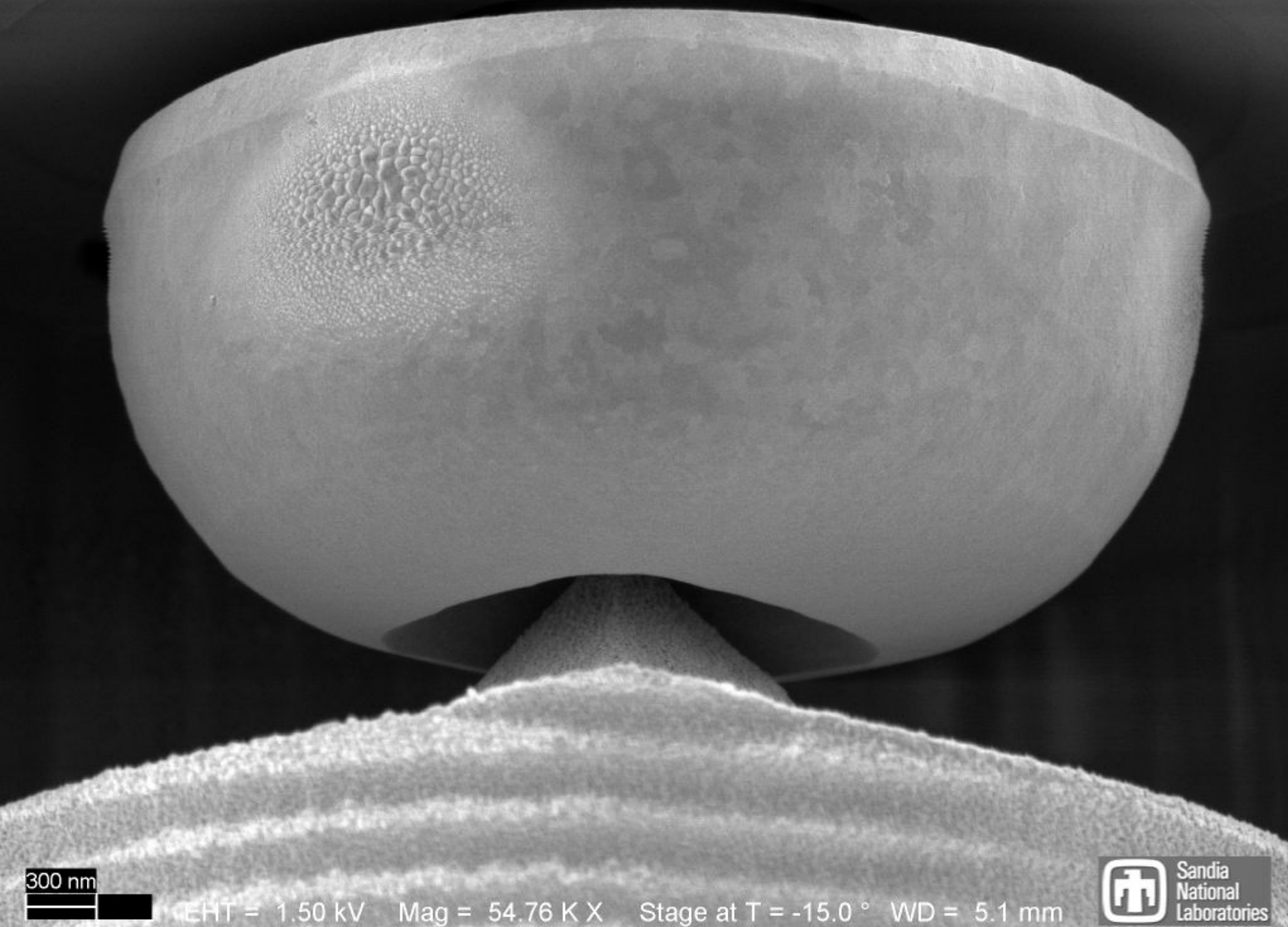
(505) 844-2072

[www.mems.sandia.gov](http://www.mems.sandia.gov)



BT

RD083704A-08 CENTER



300 nm

EHT = 1.50 kV Mag = 54.76 K X Stage at T = -15.0 ° WD = 5.1 mm



Sandia  
National  
Laboratories